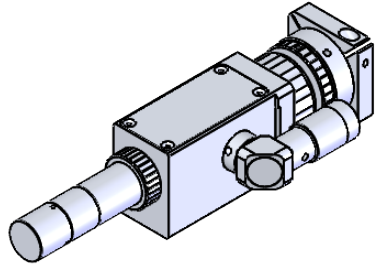
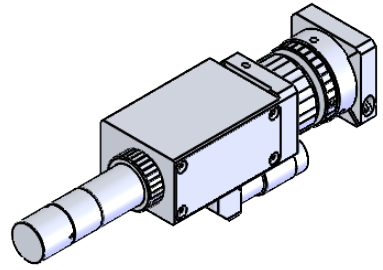
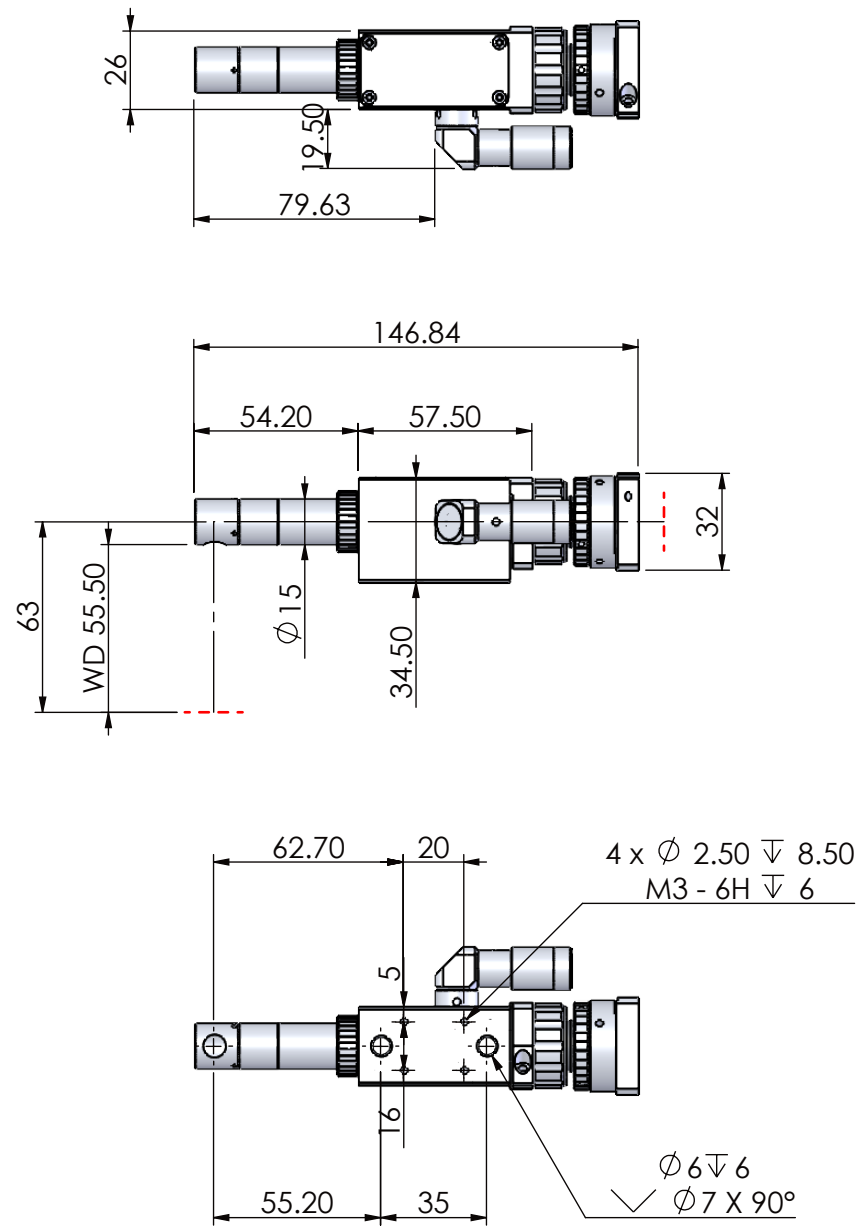


REV. NO	REVISION NOTE	DATE	SIGNATURE	CHECKED
△				

본 도면은 리스광시스템(주)의 자산이므로 허가없이 복제 및 외부 반출을 금함.
 This drawing and ideas are protected by LEES Optical System, Inc.



OPTICAL MAGNIFICATION	WD(mm)	DEPTH OF FIELD	RESOLUTION	NA	PARAXIAL WORKING F/#	F.O.V	MOUNT	SCALE	ANGLE	DESIGNED BY	CHECKED BY	APPROVED BY	TITLE	
								1:2.5						
2.5X	55.5	±0.178mm	7.5um	0.045	25.9	H2.5 X V1.9(1/2") H1.9 X V1.4(1/3")	C-MOUNT	<input checked="" type="checkbox"/> MM <input type="checkbox"/> INCH	<input checked="" type="checkbox"/> ° <input type="checkbox"/> '				MMVLS SERIES SPEC	
													DWG. NO	LP11062-R02-M00